

SUPPORTING INFORMATION

Tailoring the Chain Packing in Ultrathin Polyelectrolyte Films Formed by Sequential Adsorption: Nanoscale Probing by Positron Annihilation Spectroscopy

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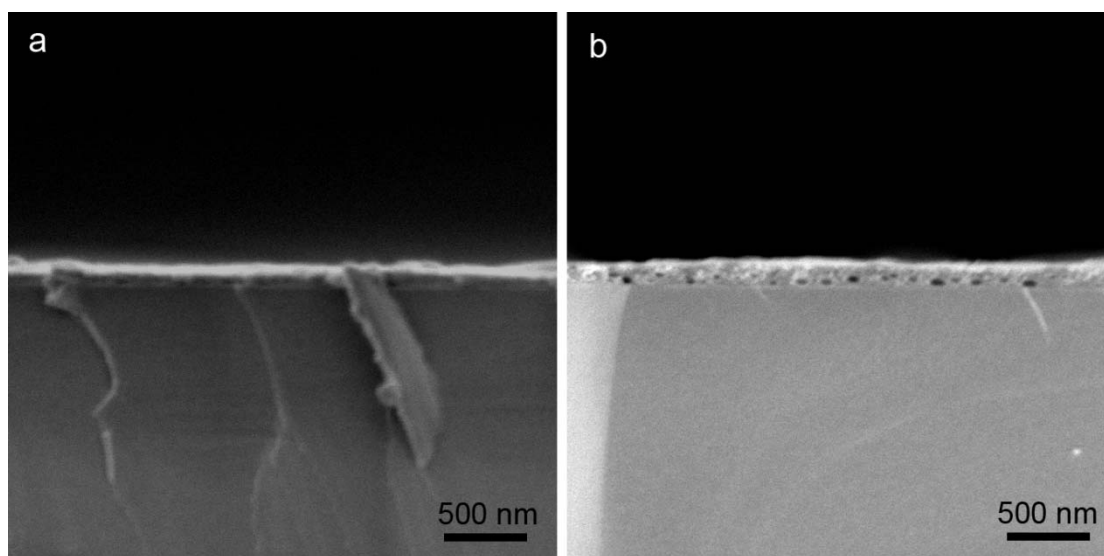


Figure S1. Cross-sectional SEM images of LbL films: (a) (PAH/PSS)₅₀ and (b) (PAH/50%PSS/50%PAA)₂₀. After film preparation, the silicon wafer substrates were cut in half and immobilized onto an SEM sample holder vertically with the cut sides facing upwards. The samples were coated with Au and imaged with a Philips XL30 SEM (operated at 2 kV). The film thicknesses determined from these images are ~120nm and ~220nm, respectively, which are in good agreement with those determined by ellipsometry and PAS. The error in these values is approximately ±15% due to the tilt angle on the samples.